



SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)			ATTY. DOCKET NO. 55071-267		SERIAL NO. 10/626,858		
			APPLICANT Stephen D. HSU, et al.				
			FILING DATE July 25, 2003		GROUP 2826		
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code(s) (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
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EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes - Number - Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
SP		HSU, Stephen D., et al. "65 nm Full-chip implementation Using Double Dipole Lithography." Optical Microlithography XVI, Santa Clara, California, USA, February 2003, Proceedings of the SPIE- The International Society for Optical Engineering, pp. 215-231, XP 009024366, ISSN: 0277-786X					
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EXAMINER <i>Quinn Parihar</i>				DATE CONSIDERED NOV 1, 2005			

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